

AMENDMENTS TO THE SPECIFICATION

Please replace paragraph no. [0026] bridging pages 8-9 of the specification with the following rewritten paragraph:

[FIG. 1] Schematic configuration of an embodiment of the apparatus for producing microparticles for forming the ITO powder of the present invention.

[FIG. 2] An X-ray diffraction chart of ITO powder produced in Example 1 of the present invention.

[FIG. 3] An X-ray diffraction chart of ITO powder produced in Example 2 of the present invention.

[FIG. 4] An X-ray diffraction chart of ITO powder produced in Comparative Example 1 of the present invention.

[FIG. 5] An X-ray diffraction chart of ITO powder produced in Comparative Example 2 of the present invention.

[FIG. 6] An X-ray diffraction chart of ITO powder produced in Comparative Example 3 of the present invention.

[FIG. 7] An X-ray diffraction chart of ITO powder produced in Example 3 of the present invention.

[FIG. 8] An X-ray diffraction chart of ITO powder produced in Comparative Example 4 of the present invention.

~~[FIG. 9] A graph showing the results of Test Example 4 in relation to the present invention.~~

Please replace paragraph no. [0094] at page 38 of the specification with the following rewritten paragraph:

<Test Example 4>

Sputtering targets produced in Production Examples 2 to 4 and Comparative Production Example 2 were analyzed in terms of arcing characteristics. Specifically, each target was subjected to continuous DC sputtering under the following conditions, and 50-counts life of the target was determined. The term "50-counts life" means total input electric power (Wh/cm^2) when the cumulative arcing count reached 50, with the exclusion of initial arcing events observed from the start of sputtering to the point in time at which the input electric power reached 10 Wh/cm^2 . Arcing was detected by means of an arcing detection apparatus (MAM Genesis, product of Landmark Technology). The results are shown in Table 4 and FIG. 9.